

AMENDMENT TO THE CLAIMS

Claims 1-3. (canceled)

4. (currently amended) [[The apparatus of claim 1,]] An apparatus for inspection and review of a substrate, the apparatus comprising:  
a first subsystem for inspecting said substrate;  
a processor for identifying regions of said substrate for review; and  
a second subsystem for reviewing at least a portion of said regions,  
wherein both said first and second subsystems each comprises an electron beam microscope,  
wherein the inspection of the substrate is performed while the substrate is on a continuously moving stage, and  
wherein review images from said regions are grabbed "on the fly" by the apparatus so as to avoid a need to relocate said regions.
5. (original) The apparatus of claim 4, wherein said first subsystem and said second subsystem share one or more electron optical elements in common.
6. (original) The apparatus of claim 5, wherein said first subsystem and said second subsystem share substantially all electron optical elements in common.
7. (original) The apparatus of claim 4, wherein said portion is reviewed at a second condition differing from a first condition under which said portion is inspected.

8. (original) The apparatus of claim 4, wherein said portion is reviewed at a second condition differing from a first condition under which said portion is inspected.
9. (original) The apparatus of claim 8, wherein said first condition and said second condition differ from one another with regard to at least one parameter selected from the group including: true perspective; apparent perspective; magnification; and contrast.
10. (currently amended) The apparatus of [[claim 1]] claim 4, wherein said first subsystem comprises a LEEM.
11. (currently amended) The apparatus of [[claim 1]] claim 4, wherein said second subsystem comprises a LEEM.
12. (currently amended) The apparatus of [[claim 1]] claim 4, wherein both said first and second subsystems each comprises a LEEM.
13. (original) The apparatus of claim 12, wherein said first subsystem and said second subsystem share one or more electron optical elements in common.
14. (original) The apparatus of claim 13, wherein said first subsystem and said second subsystem share substantially all electron optical elements in common.
15. (original) The apparatus of claim 12, wherein said portion is reviewed at a second condition differing from a first condition under which said portion is inspected.
16. (original) The apparatus of claim 15, wherein said first condition and said second condition differ from one another with regard to at least one

parameter selected from the group including: true perspective; apparent perspective; magnification; and contrast.

Claims 17-18. Canceled

19. (currently amended) [[The method of claim 18,]] A method for inspection and review of a substrate, the method comprising:  
inspecting said substrate in an apparatus to generate inspection data;  
processing the inspection data to identify regions of said substrate for  
review; and  
reviewing at least a portion of said regions in the apparatus,  
wherein the inspecting is performed using a first subsystem of the  
apparatus,  
wherein the reviewing is performed using a second subsystem of the  
apparatus,  
wherein said portion is reviewed at a second condition differing from a first condition under which said portion is inspected,  
wherein the inspection of the substrate is performed while the substrate is  
on a continuously moving stage, and  
wherein review images from said regions are grabbed "on the fly" by the  
apparatus so as to avoid a need to relocate said regions.
20. (original) The method of claim 19, wherein said first condition and said second condition differ from one another with regard to at least one parameter selected from the group including: true perspective; apparent perspective; magnification; and contrast.